

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S1	10733	134/113 156/345 156/345.\$ 156/8 216/88 216/89 216/90 216/83	USPAT	OR	OFF	2006/08/14 17:00
S2	767	216/100 216/95 216/91	USPAT	OR	OFF	2005/05/17 13:20
S3	11147	S1 S2	USPAT	OR	OFF	2005/05/17 13:20
S4	2031	S3 and (semiconductor wafer substrate) with (vertical\$2 nonhorizontal)	USPAT	OR	OFF	2005/05/17 13:22
S5	1648	S4 and (etch\$3 dip\$4 bath container)	USPAT	OR	OFF	2005/05/17 13:22
S6	1061	S5 and (metal copper)	USPAT	OR	OFF	2005/05/17 13:23
S7	198	S5 and (metal copper) same (edge peripher\$4)	USPAT	OR	OFF	2005/05/17 14:18
S8	29674	wet with etch\$3	USPAT	OR	OFF	2005/05/17 14:18
S9	574	S8 with vertical\$2	USPAT	OR	OFF	2005/05/17 14:19
S10	45100	(dip\$4 wet immers\$4) with (wafer substrate semiconductor)	USPAT	OR	OFF	2005/05/17 14:20
S11	668	S10 with vertical\$2	USPAT	OR	OFF	2005/06/03 15:10
S12	1107	S9 S11	USPAT	OR	OFF	2005/05/17 14:20
S13	43712	chuck sme bath same (semiconductor wafer)	USPAT	OR	OFF	2005/05/31 14:03
S14	97	chuck same bath same (semiconductor wafer)	USPAT	OR	OFF	2005/05/31 14:16
S15	3	("6625835" "20030209255" "20020040888" "6290865" "3898095").pn.	USPAT	OR	OFF	2005/05/31 14:17
S16	5	("6625835" "20030209255" "20020040888" "6290865" "3898095").pn.	US-PGPUB; USPAT	OR	OFF	2005/05/31 14:17
S17	3195	"taiwan semiconductor manufacturing"	USPAT	OR	OFF	2006/03/03 16:02
S18	4	S17 and (chuck same bath)	USPAT	OR	OFF	2005/05/31 14:44
S19	2499	S17 and (bath tank dip\$4 etch\$3)	USPAT	OR	OFF	2005/05/31 14:45
S20	544	S19 and (chuck holder table)	USPAT	OR	OFF	2005/05/31 14:45
S21	179	"taiwan semiconductor manufacturing" and (bath tank dip\$4 etch\$3)same (chuck holder table)	USPAT	OR	OFF	2005/05/31 15:37
S22	728	134/113	USPAT	OR	OFF	2005/05/31 14:56
S23	172	S22 and (semiconductor wafer)	USPAT	OR	OFF	2005/05/31 15:20
S24	1716	(sccm "ml/min") same etch\$3 same (wafer semiconductor)	USPAT	OR	OFF	2005/05/31 15:37

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S25	977	(sccm "ml/min") with etch\$3 same (wafer semiconductor)	USPAT	OR	OFF	2005/05/31 15:23
S26	5	S25 same (bath tank)	USPAT	OR	OFF	2005/05/31 15:26
S27	71	S17 and S25	USPAT	OR	OFF	2005/05/31 15:27
S28	3	S27 not plasma	USPAT	OR	OFF	2005/05/31 15:28
S29	97	S25 not (plasma)	USPAT	OR	OFF	2005/05/31 15:28
S30	94	S29 not S28	USPAT	OR	OFF	2005/05/31 15:28
S31	78	(sccm "ml/min") and S21	USPAT	OR	OFF	2005/05/31 15:42
S32	41148	"ml/min"	USPAT	OR	OFF	2005/05/31 15:50
S33	1908	S32 and etch\$3	USPAT	OR	OFF	2005/05/31 15:42
S34	384	S33 and (fluid not plasma)	USPAT	OR	OFF	2005/05/31 15:43
S35	3539	"ml/min" with (fluid liquid)	USPAT	OR	OFF	2005/05/31 15:50
S36	9	S35 same etch\$3	USPAT	OR	OFF	2005/05/31 15:52
S37	1	"6051505".pn.	USPAT	OR	OFF	2005/05/31 15:54
S38	1	S37 and sccm	USPAT	OR	OFF	2005/05/31 15:52
S39	45275	(dip\$4 wet immers\$4) with (wafer substrate semiconductor)	USPAT	OR	OFF	2005/06/03 15:10
S40	673	S39 with vertical\$2	USPAT	OR	OFF	2005/06/03 15:11
S41	82463	((dip\$4 vertical\$2 (up and down)) and (bath etch tank)) and (wafer substrate semiconductor)	USPAT	OR	OFF	2005/06/06 10:02
S42	9613	((dip\$4 vertical\$2 (up and down)) same (bath etch tank)) same (wafer substrate semiconductor)	USPAT	OR	OFF	2005/06/06 10:03
S43	3114	((dip\$4 vertical\$2 (up and down)) with (bath etch tank)) with (wafer substrate semiconductor)	USPAT	OR	OFF	2005/06/06 10:04
S44	1254	S43 and ("134"/\$ 156/345.\$ "216"/\$ "438"/\$)	USPAT	OR	OFF	2005/06/06 10:06
S45	14	"20020040888" "3898095"	USPAT	OR	OFF	2005/06/06 13:20
S46	1	"20020040888"	US-PGPUB; USPAT	OR	OFF	2005/06/06 15:05
S47	31906	("sulfuric acid" and "hydrogen peroxide" "di water")	US-PGPUB; USPAT	OR	OFF	2005/06/06 15:06
S48	30	("sulfuric acid" with "hydrogen peroxide" with "di water")	US-PGPUB; USPAT	OR	OFF	2005/06/06 15:29
S49	3114	((dip\$4 vertical\$2 (up and down)) with (bath etch tank)) with (wafer substrate semiconductor)	USPAT	OR	OFF	2005/06/06 15:29
S50	1254	S49 and ("134"/\$ 156/345.\$ "216"/\$ "438"/\$)	USPAT	OR	OFF	2005/06/06 15:29

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S51	78	S50 and rpm	US-PGPUB; USPAT	OR	OFF	2005/06/06 15:29
S52	0	"edge removal" same rinse	USPAT	OR	OFF	2005/06/07 11:13
S53	111	"edge bead" and rinse	USPAT	OR	OFF	2005/06/07 11:14
S54	8	((("6135724") or ("3964957") or ("3898095") or ("6015505") or ("20030209255") or ("6539963") or ("6641708") or ("5593505")).PN.	US-PGPUB; USPAT	OR	OFF	2005/11/07 13:47
S55	1	("6136724").PN.	US-PGPUB; USPAT	OR	OFF	2005/11/07 13:47
S56	12923	134/113 156/345 156/345.11 156/345.55 156/8 216/88 216/89 216/90 216/83 134/902 134/149 134/157 134/159	US-PGPUB; USPAT	OR	OFF	2005/11/07 14:03
S57	250340	(rotat\$3 turn\$3 spin\$4 pivot\$4) with (hold\$3 support\$3 chuck\$3) same (slid\$3 vertical\$2 up dip\$4)	US-PGPUB; USPAT	OR	OFF	2005/11/08 16:35
S58	1471	S56 and S57	US-PGPUB; USPAT	OR	OFF	2005/11/07 14:05
S59	1177	S58 and (wafer semiconductor)	US-PGPUB; USPAT	OR	OFF	2005/11/07 14:05
S60	1101	S59 and (wash\$3 rins\$3 clean\$3 etch\$3)	US-PGPUB; USPAT	OR	OFF	2005/11/07 14:42
S61	0	"hung-wen su" "ming-hsing tsai"	US-PGPUB; USPAT	OR	OFF	2005/11/07 14:42
S62	5	su-hung.in. tsai-ming.in.	US-PGPUB; USPAT	OR	OFF	2005/11/07 14:43
S63	9	su-wen.in. tsia-hsing.in.	US-PGPUB; USPAT	OR	OFF	2005/11/07 14:44
S64	8	su-"hung-wen".in.	US-PGPUB; USPAT	OR	OFF	2005/11/07 14:46
S65	39	tsai-"ming-hsing".in.	US-PGPUB; USPAT	OR	OFF	2005/11/07 14:45
S66	66	156/345.23	US-PGPUB; USPAT	OR	OFF	2005/11/07 14:46
S67	476	dip\$4 with (etch\$3 clean\$3 wash\$3 rins\$3) with (wafer semicondutor)	EPO; JPO; DERWENT	OR	OFF	2005/11/08 16:36
S68	114147	(rotat\$3 turn\$3 spin\$4 pivot\$4) with (hold\$3 support\$3 chuck\$3) same (slid\$3 vertical\$2 up dip\$4)	EPO; JPO; DERWENT	OR	OFF	2005/11/08 16:36
S69	1427	((rotat\$3 turn\$3 spin\$4 pivot\$4) with (hold\$3 support\$3 chuck\$3) same (slid\$3 vertical\$2 up dip\$4)) same (wafer semiconductor)	EPO; JPO; DERWENT	OR	OFF	2005/11/08 16:36

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S70	790	dip\$4 with (etch\$3 clean\$3 wash\$3 rins\$3) with (wafer semiconductor)	EPO; JPO; DERWENT	OR	OFF	2005/11/08 16:36
S71	17	S69 and S70	EPO; JPO; DERWENT	OR	OFF	2005/11/08 16:36
S72	2	"6641708".pn. "6051505".pn.	USPAT	OR	OFF	2005/11/10 16:04
S73	6	((("6797074") or ("6523553") or ("6070284") or ("6055694") or ("5933902") or ("4897369"))).PN.	US-PGPUB; USPAT	OR	OFF	2006/03/03 15:58
S74	6	("4897369").URPN.	USPAT	OR	OFF	2006/03/03 16:01
S75	3477	"taiwan semiconductor manufacturing"	USPAT	OR	OFF	2006/03/03 16:02
S76	413	S75 and (clean\$3 wash\$3 remov\$3 etch\$3) same (edge side peripher\$3)with (wafer semiconductor substrate)	USPAT	OR	OFF	2006/03/03 16:15
S77	2262	((clean\$3 wash\$3 remov\$3 etch\$3) same (edge side peripher\$3)with (wafer semiconductor substrate)) and (156/345.11 156/345.55 "134"/\$)	USPAT	OR	OFF	2006/03/03 16:17
S78	1627	((clean\$3 wash\$3 remov\$3 etch\$3) with(edge side peripher\$3)with (wafer semiconductor substrate)) and (156/345.11 156/345.55 "134"/\$)	USPAT	OR	OFF	2006/03/03 16:17
S79	2097	((clean\$3 wash\$3 remov\$3 etch\$3) with(edge side peripher\$3)with (wafer semiconductor substrate)) and (156/345.11 156/345.55 "134"/\$)	US-PGPUB; USPAT	OR	OFF	2006/03/03 16:18
S80	2062	S79 not S76	US-PGPUB; USPAT	OR	OFF	2006/03/03 16:18
S81	1427	S80 and (rotat\$3 spin\$3 turn\$5) with (wafer substrate semiconductor)	US-PGPUB; USPAT	OR	OFF	2006/03/03 16:19
S82	912	S81 and (dip\$4 lift\$3 vertical\$2) with (substrate wafer semiconductor)	US-PGPUB; USPAT	OR	OFF	2006/03/03 16:19
S83	996	134/113 156/345.55	US-PGPUB; USPAT	OR	OFF	2006/08/15 12:16
S84	3	"6764386" "6869890"	US-PGPUB; USPAT	OR	OFF	2006/08/15 12:16